

TRANSFER UNIT

ABSTRACT

A transfer unit transferring a wafer from or to a cassette is provided. The transfer unit includes a holding portion holding the wafer under suction and a driving portion moving the holding portion. The holding portion includes a body, a plurality of suction openings formed on the upper surface of the body so as to be spaced from each other, a vacuum transmitting passage connected to a vacuum source for transmitting a vacuum from the vacuum source to the suction openings, and a plurality of suction pads provided at the suction openings, each suction pad being formed of an elastic material. The suction openings are spaced from each other in the radial direction of the wafer, and the suction pads are selectively provided at any desired ones of the suction openings.

(Figure 2)